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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of)
Koichiro TANAKA)
Japanese Priority Application 2000-024615) Attn: Applications
Japanese Priority Date: February 2, 2000) Branch
For: BEAM HOMOGENIZER, LASER)
IRRADIATION APPARATUS,)
SEMICONDUCTOR DEVICE, AND)
METHOD OF FABRICATING THE)
SEMICONDUCTOR DEVICE) Date: February 1, 2001

PRELIMINARY AMENDMENT

Honorable Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Please preliminarily amend the subject application as follows:

IN THE SPECIFICATION:

Page 18, line 16, change "Figs. 13A and 13B" to --Figs. 13A, 13B and 13C--.

REMARKS

This application has been amended to correct the brief description of Figure
13.